

process module	E-rack	Gasbox	trasport module	Comm Chamber
heated lower chamber assy - integrated 700W cartridge heaters - painted steel support frame -pneaumatic air regulator	**source generator** MKS Surepower 6.5KW 13.56 RF Power supply	gases selected : C4F8 400sccm SF6 1200 sccm O2 200 sccm AR 200 sccm N2 100 sccm N2 100 sccm	**automatic carousel vacuum loadlock** -single point hook-up -DI water, facilities water ,He,N2, CDA , power	**Edwards IH600 Connection kit**
process module facilities service panel - N2, comp air ,house water , He , power	**lower electrode HF RF Generator** ENI ACG3B 300/30W 13.56 MHz RF power supply		**carousel small batch operation** **2x200mm batch**	**Foreline self regulated heater jacket**
Helium substrate backside cooling - integrated MKS 649 dual-zone pressure controller	**Lower electrode LF RF Generator** advanced energy LF5 500W 50-450 KHz RF Power supply		**200mm end effector for carousel**	**Chiller for lower Electrode temperature control** -SMC HRZ DeviceNet - -20 C to 40 C - Galden coolant - Foam insulated chiller pipework (6 m)
process module transfer valve -VAT series 021 rectangular valve - VITON seals	**20amp electromagnet PSU UNIT**		**device net signal tower 4 lights**	**Chiller for antenna temperature control** -SMC HRG - +5 C to + 40 C - DI Water coolant
MAG DRIVE 2000 Turbo pump - lybold MAG 2000 pump -Heated ISO 250 VAT series 65.1 pendulum valve with on-board devicenet controller	**10amp electromagnet PSU assembly**		**cleanroom panel integrated operator control panel** - compatible with semi-standart 100mm thick walls - 18" touchscreen display -Keyboard with trackball	
Lower Electrode RF enclosure - SMS electrode and wafer lift pneumatics -DC bias and PK-PK voltage detection	**400V AC distribution**		**transport module pumping** Varian TS600 cleanroom compatible scroll pump	
Anti condensation kit for low temperature processes	**pegasus inner window clamp tool**		**BOSCH switched processing license package**	
Lower Electrode RF matching unit - HF and LF capability for enhanced SOI process package				
Process module vacuum gauge kit - high vacuum active inverted magnetron gauge - 5mBar over pressure switch - MKS 750 capacitance manometre 10 Torr for foreline pressure - Bypass pumping valve valve with MKS 750 10 Torr capacitance manometre				
process pressure measurement - heated MKS capacitance manometer 250 mTorr -STS Advanced pressure control. Optimised pressure control during both the etch and deposition step when used in the bosch process				
PRO2 module 400C AC panel				
On-board DC sysytems control - DeviceNet nodes for digital and analogue I/O - DeviceNet temperature controller				
Magnetic plasma confinament chamber - plasma source assembly is hinged for easy maintenance access				
Pegasus decoupled ICP plasma source assembly - electromagnetic ion attenuation - pre-heated temperature controlled internal source components for process stability - Verity Instruments SD1024F Smart Spectrograph EPD				
STS smooth sidewall process gas distribution -close-coupled fast response sensiron MFCs -1200 sccm SF6 -400sccm C4F8 -200 sccm O2				